

IN THE CLAIMS:

This listing of claims will replace all prior versions, and listing, of claims in the application:

1. (Previously Presented) A lithographic projection apparatus comprising:
 - a radiation system to provide a projection beam of radiation;
 - a first object table adapted to support patterning structure which can be used to pattern the projection beam according to a desired pattern;
 - a second object table to hold a substrate;
 - a vacuum chamber provided with a first vacuum generator constructed and arranged to provide a vacuum beam path for the projection beam;
 - a projection system to project the patterned beam onto a target portion of the substrate;
 - at least one conduit communicating a utility to a component of said lithographic projection apparatus moveable in at least one degree of freedom in said vacuum chamber;
 - a conduit shield substantially enclosing a space comprising the at least one conduit and substantially separating said vacuum chamber from the space comprising the at least one conduit, said conduit shield being constructed and arranged to allow for movement of the component in said at least one degree of freedom, and
 - a second vacuum generator constructed and arranged to provide a vacuum in the space comprising the at least one conduit.
2. (Original) A lithographic projection apparatus according to claim 1, wherein said conduit shield comprises a conduit conduct to guide and shield said at least one conduit.
3. (Original) A lithographic projection apparatus according to claim 2, wherein said conduit conduct has at least two joints.
4. (Original) A lithographic projection apparatus according to claim 2, wherein said conduit conduct comprises at least one hollow elongate arm portion.

5. (Original) A lithographic projection apparatus according to claim 4, wherein said at least one hollow elongate arm portion is translatable along its elongate direction relative to another structure at a translation joint.

6. (Currently Amended) A lithographic projection apparatus according to claim 1, wherein said vacuum provided with said second vacuum generator to the space comprising the at least one conduit has a higher pressure than the pressure of the vacuum provided with said first ~~gas evacuating means to the vacuum chamber~~ vacuum generator.

7. (Currently Amended) A lithographic projection apparatus according to claim 3, wherein moving co-operating surfaces of said ~~joint~~ joints are furnished with vacuum seals.

8. (Currently Amended) A lithographic projection apparatus according to claim 1, wherein said component is an object table and said ~~conduits are~~ at least one conduit is constructed and arranged to communicate ~~utilities~~ the utility to said object table.

9. (Currently Amended) A device manufacturing method using a lithographic apparatus comprising:

projecting a patterned projection beam of radiation through a vacuum chamber onto a target portion of a substrate that is at least partially covered by a layer of radiation-sensitive material;

providing a utility through a conduit to a moveable component of the lithographic projection apparatus, which component is disposed in said vacuum chamber;

shielding a vacuum in said vacuum chamber from said ~~conduits~~ conduit with a conduit shield;

moving said conduit shield in accordance with movement of the moveable component; and

providing a second vacuum in a space comprising the ~~conduits~~ conduit and separated by the conduit shield from said vacuum chamber.

10. (Original) A device manufactured in accordance with the method of claim 9.

11. (Original) A lithographic projection apparatus, comprising:
 - a radiation system that provides a beam of radiation;
 - a first object table adapted to support patterning structure which can be used to pattern the projection beam according to a desired pattern;
 - a second object table for holding a substrate;
 - a first vacuum region carrying a vacuum through which said projection beam travels;
 - a projection system that projects the patterned beam onto a target portion of the substrate;
 - a conduit communicating a utility to a component of said lithographic projection apparatus moveable within said first vacuum region;
 - a second vacuum region within which said conduit is disposed; and
 - a conduit shield separating said first vacuum region from said second vacuum region, said conduit shield permitting movement of said component within said first vacuum region.